

ASMJP.032AUS



PATENT

9B
8H
9/26/02
EX.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Fukuda et al.)	Group Art Unit 1763
Appl. No.	:	09/511,934)	
Filed	:	February 24, 2000)	
For	:	THIN-FILM FORMING APPARATUS HAVING AN AUTOMATIC CLEANING FUNCTION FOR CLEANING THE INSIDE)	
Examiner	:	R. Kackar)	

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SEP 25 2002
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AMENDMENT AFTER FINAL

Assistant Commissioner for Patents

Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed July 1, 2002 (Paper number 8), please amend the above-captioned application as follows:

IN THE CLAIMS:

Please amend Claim 1 as follows:

~~1. (Twice amended) A thin film forming apparatus comprising:~~

~~a reaction chamber for forming at a film formation temperature a thin film on a workpiece~~

~~placed on a susceptor provided in the reaction chamber, said susceptor being made of aluminum nitride and provided with a heater for heating the workpiece, said reaction chamber being provided with a conveyer for loading and unloading the workpiece into and from the reaction chamber; and~~

~~a cleaning device for cleaning unwanted deposits adhering to the inside of the reaction chamber at predetermined intervals, said cleaning device comprising:~~